

EUROPEAN 3D SUMMIT 2016
MINATEC 18,19 and 20 january 2016
LIST OF PARTICIPANTS

Nom	Prenom	Organisation
ACHTSNICK	Marcel	Berliner Glas KGaA Herbert Kubatz GmbH & Co
ALAPATI	Ramakanth	GLOBALFOUNDRIES
ALBERT	Ou	ASE group
ALTIMIME	Laith	SEMI Europe
ANDERSON	Timothy	FOGALE nanotech
ANDRE	Didier	TEL NEXX
ARGOUD	Maxime	CEA-Leti
ARKALGUD	Sitaram	Invensas
ARNAUD	Lucile	CEA-Leti
ARRIORDAZ	Alexandre	Mentor Graphics
ARROYO	Jean-Pierre	STMicroelectronics
ASTIER	Alain	A2C2
ATTARD	Alastair	Besi Austria GmbH
AUDOIT	Guillaume	CEA-Leti
AUER	Hans	Evatec
AVRILLIER	Caroline	SET
AWDSHIEW	Michael	Ultratech GmbH
BAATARD	Francois	Besi
BAI	Dongshun	Brewer Science, Inc.
BAL	Linda	TechSearch International, Inc
BARNY	Antonio	NANIUM S.A.
BASAEV	Alexander	SMC Technological Centre
BAUD	Laurence	CEA-Leti
BEICA	Rozalia	Yole
BEISL	Daniel	Siconnex
BEIX	Vincent	ALEDIA
BELOUS	Anatoly	JSC
BERNARD	David	Nordson DAGE
BERNARD-MOULIN	Elsa	CORIAL SAS
BERNS	Andreas	VDI/VDE Innovation + Technik GmbH
BERTOLASI	Paul	ASE Group
BEYER	Gerald	IMEC
BEYNE	Eric	Imec
BLEUET	Pierre	CEA-Leti
BOBENSTETTER	Otto	EV Group (EVG)
BOOMSMA	Ruurd	Besi
BOUTANT	Jerome	SEMI Grenoble
BRALL	Claudia	Fraunhofer IZM
BRAUN	Stephan	Sensirion AG
BRIZOUX	Michel	Thales Global Services
BROOKS	Brandon	AMAT
BUCHANAN	Iain	Air Products
BUTLER	David	SPTS
CADIX	Lionel	ASE
CARGEMEL	Laurent	ATOS
CARZANIGA	Andrea	MICROCONTROL ELECTRONIC SRL
CHARBONNIER	Jean	CEA-Leti
CHATTAWAY	Emily	Class One technology
CHERAMY	Severine	CEA-Leti
CIGAL	Jean-Charles	Linde AG
DAVIOT	Jerome	Technic
DE KERCKHOVE	Alexandre	CMOSIS
DELABRE	Herve	AEMtec GmbH
DESJARDINS	Patrick	Kulicke and Soffa
DEVANCIARD	Nicolas	CEA-Leti
DOUASS	Hassan	DISCO HI-TEC FRANCE SARL
DOUDOU	Cyril	Brewer Science
DUDKIN	Alexandr	JSC "INTEGRAL"- "INTEGRAL" Holding Managing Company
DUTRON	Anne-Marie	SEMI Europe
EBEFORS	Thorbjorn	Silex

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EDE	James	Class One
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EUVRARD	Catherine	CEA-Leti
FACTOR	Bradford	ASE Group
FADLOUN	Sabrina	SPTS
FAJARDO	Pablo	ESRF
FITAMANT	Christophe	Aveni
FONG	Ted	SiGen
FRAUX	Romain	System Plus Consulting
FRESQUET	Gilles	FOGALE nanotech
FRIES	Thomas	FRT, Fries Research & Technology GmbH
FRITSCH	Christina	SEMI Europe
GABETTE	Laurence	CEA-Leti
GARNIER	Michel	STMicroelectronics
GAUDIN	Gweltaz	Soitec
GEORGEL	Vincent	e2v semiconductors
GHANNAM	Ayad	3DiS Technologies
GHYSELEN	Bruno	SOITEC
GOTTFRIED	Knut	Fraunhofer ENAS
GOUBAULT	Baptiste	CEA-Leti
GOUYOU	Francois	Valeo
GROMMES	Walther	3M
GRUSS	Gunar	pmdtechnologies
GUILLOU	Yann	SEMI Europe
GUYADER	François	STMicroelectronics
HACKSTEINER	Markus	MTI GmbH
HARRISON	Robert	24IP Law Group
HASSEL SHEARER	Michael	Gatan UK
HEINIG	Andy	Fraunhofer Institute for Integrated Circuits (IIS), Design Automation Division (EAS)
HERAUD	Stephane	NOVA MEASURING INSTRUMENTS GMBH
HINER	Dave	AMKOR Technology
HINTZ	Gerd	Comet
HO	Yens	Xintec
HOPKINS	David	Amkor
HOTELLIER	Nicolas	STMicroelectronics
IKEHATA	Ken	Takatori Corporation
IMBS	Yvon	STMicroelectronics
JAFFARD	Jean-Luc	Redbelt Conseil
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JEDWAB	Serge	Siconnex
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JOUVE	Amandine	CEA-Leti
KAIRE	David	STMicroelectronics
KARPUSHIN	Mikhail	Ikar - Impulse Ltd
KATZ	Omri	Camtek
KIMMICH	Georg	STMicroelectronics
KLAUSHOFER	Thomas	Siconnex
KLINGER	Jan	HSEB Dresden GmbH
KNIPPELMEYER	Rainer	R&K Technologies UG
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KONDO	Kazuo	Fine Feature Electrodeposition Research Institute
KROEHNERT	Stephen	NANIUM S.A.
LABUNOU	Uladzimir	JSC "INTEGRAL"- "INTEGRAL" Holding Managing Company
LANDRY	Karine	Merck Performance Materials
LATTARD	Didier	CEA-Leti
LAZERAND	Thierry	Plasma-Therm, LLC
LE-BRIZ	Olivier	STMicroelectronics
LECARPENTIER	Gilbert	PLASMA THERM
LEE	Jia	Veeco Instruments
LEFEVRE	Matthew	JOHN P. KUMMER
LEHMANN	Lars	PMDTechnologies

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LEVEQUE	Bertrand	Nikon Precision Europe Gmbh
LHOSTIS	Sandrine	STMicroelectronics
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LOPES DOS SANTOS	Cristiano	CEA-Leti
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LUDWIG	Marko	Corning
LUJAN	Amy	SavanSys Solutions LLC
LUNDAHL	Karl	Fingerprints Cards AB
LUTTER	Stefan	SUSS
MACLEOD	Patricia	ASE
MACNEIL	John	Picofluidics Limited
MANOLESCU	Dan	eSilicon
MARQUEBIELLE	Gerard	Thales Optronique
MAURON	Frederic	Aptasic SA
MAY	Michael	CEA-Leti
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MEIJER	Peter	Lam Research
MEILER	Josef	EV Group (EVG)
MENEGHEL	Daniel	Brooks Instrument
MICHAÏLOS	Jean	STMicroelectronics
MOITZI	Heinz	AT&S
MOLENAAR	Pete	TOWA Europe B.V. PDC
MOREL	Bruno	Aveni
MOULIN	Cecile	CEA LETI
MOURIER	Thierry	CEA-Leti
MOYSE	Philip	Nordson DAGE
NAL	Patrice	ALTATECH
NOAKES	Andy	SPTS
OMAHONY	Conor	Comet Technologies USA
ÖTZLINGER	Herbert	Semsysco
OUERD	Aziz	Air Liquide Electronics Systems
PALESKO	Chet	SavanSys Solutions LLC
PARES	Gabriel	CEA-Leti
PEQUIGNAT	Veronique	AEPI - invest in Grenoble-isere, France
PERRIN	Patrice	SPTS
PERROCHEAU	Jacques	PLASMA THERM
PETRACCI	Marine	INSIGHT OUTSIDE
PEYRE	Georges	Rockwood Wafer Reclaim
PIALLAT	Fabien	ALTATECH
PITARD	Frederic	AMAT
POPOV	Aleksei	OAO NIET
POUPON	Gilles	CEA-Leti
PRIEWASSER	Karl	DISCO HI-TEC FRANCE SARL
PRISTAUZ	Hugo	BESI
QUINN	James	Scint-X
RABINZOHN	Patrick	Lam Research
RAYNAL	Frederic	Aveni
RAYNAUD	Nicolas	SET corporation
REINWALD	Matthias	Infineon Technologies
REY	Juan	Mentor Graphics
RIEDEL	Thomas	S3-ALLIANCE
RIVIERE	Jean-Michel	STMicroelectronics
ROYAL	Helen	Plasma-Therm, LLC
RUDOLPH	Catharina	Fraunhofer IZM
RUTHERFORD	Iain	X-FAB
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SANCHEZ	Loïc	CEA
SARIOGLU	Hosgoer	SUSS MicroTec Lithography GmbH
SAUGIER	Eric	STMicroelectronics
SCHAEFER	Christian	Trymax

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SCHICKE	Matthias	Fujifilm
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SCHRANK	Franz	ams AG
SCHREMS	Martin	ams AG
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SEILLER	Jacky	Amkor
SHAPIRA	Shye	Camtek Ltd.
SIEGERT	Joerg	ams AG
SIMON	Gilles	CEA-Leti
SPRENGARD	Ruediger	SCHOTT AG
STOERRING	Moritz	KLA-Tencor
SUDAN	Jacques-André	ETEL S.A.
TANIGAWA	Ryuki	Takatori Corporation
TERRAT	Sabrina	SEMI Europe
THIELERT	Frank	Confovis GmbH
THOMPSON	Peter	JTA Equipment Technology
THORUM	Matthew	Lam Research
TINGAY	John	Nordson Dage
UHRMANN	Thomas	EV Group
UVAROV	Andrei	CORIAL SAS
VAL	Christian	PACKAGING SIP
VAN DER VOORT	Jelle	Liteq B.V.
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VAN HEERDEN	David	Materion
VAN HEUMEN	Wim	Trymax
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VANDROUX	Laurent	CEA-Leti
VANROMPAY	Annouck	IMEC
VANRUMBEKE	Jerome	E2V SEMICONDUCTORS
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VEZZU	Alain	STMicroelectronics
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ZHELEZNYAK	Yaniv	SELA
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ZSCHECH	Ehrenfried	Fraunhofer IZM